

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: Ki-yeon Park et al.

Serial No.: 10/828,596

Filed: April 21, 2004

For: METHODS OF FORMING METAL THIN FILMS, LANTHANUM OXIDE  
FILMS AND HIGH DIELECTRIC FILMS FOR SEMICONDUCTOR  
DEVICES USING ATOMIC LAYER DEPOSITION

Confirmation No.: 5520

Examiner: Ori Nadav

Group Art Unit: 2811

February 20, 2007

Commissioner for Patents

P. O. Box 1450

Alexandria, VA 22313-1450

**RESPONSE TO NOTICE OF NON-COMPLIANT AMENDMENT**

Sir:

The present Response to Notice of Non-Compliant Amendment is being filed to address the issues raised in the Notice of Non-Compliant Amendment dated January 22, 2007.

It is not believed that an extension of time and/or additional fee(s)-including fees for net addition of claims-are required, beyond those that may otherwise be provided for in documents accompanying this paper. In the event, however, that an extension of time is necessary to allow consideration of this paper, such an extension is hereby petitioned under 37 C.F.R. §1.136(a). Any additional fees believed to be due in connection with this paper may be charged to our Deposit Account No. 50-0220.

**Listing of Claims** begin on Page 2 of this paper.

**Remarks** begin on Page 12 of this paper.